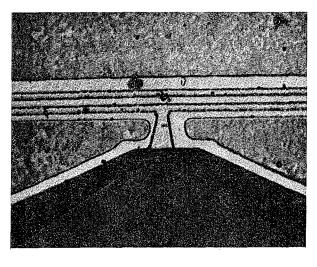
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METALLURGICAL SOCIETY OF AIM

CALIFORNIA NORTHERN



**ACOUSTIC MICROGRAPH** 

THE

NORTHERN CALIFORNIA METALLURGICAL SECTION

OF AIME

**PRESENTS** 

THE EIGHTH ANNUAL

### ELECTRONIC MATERIALS SYMPOSIUM

A One-Day Symposium on Electronic Materials Featuring Outstanding Authorities in Their Respective Fields

**HYATT PALO ALTO** 

4290 EL CAMINO REAL

PALO ALTO, CA 94306

**THURSDAY** 

March 13, 1980

7:30 A.M.

### **PROGRAM**

## Thursday, March 13, 1980 Hyatt Palo Alto

7:30 Registration

MORNING SESSION (Circus Maximus Central)

Dr. Dilip Rajdev Lockheed MSC Sunnyvale, CA

Welcoming Remarks and Introduction Dr. Robert D. Burnham Xerox PARC Palo Alto, CA 8:30

"GaAs IC's for Ultra-High Frequency VLSI" Dr. Richard C. Eden Rockwell International Thousand Oaks, CA

"The Practical Limits of MOS VLSI" Dr. Richard D. Pashley Intel Corporation Santa Clara, CA

10:20 COFFEE BREAK

10:50 "Materials Technology Challenges in GaAs for IC Development"
Dr. D. Howard Phillips
Lockheed MSC

11:45 LUNCHEON (Circus Maximus North)

12:20 Ross N. Tucker Memorial Award Presentation to Richard Gold, Department of Electrical Engineering, Stanford University, Stanford, CA

12:30 "Electronic and Energy Applications of New Amorphous Synthetic Materials' Stanford R. Owshinsky Energy Conversion Devices, Inc. Troy, MI

AFTERNOON SESSION (Circus Maximum Central)

Session Chairman: Frank Perlaki Hewlett-Packard Corp. Palo Alto, CA

"Application of CW Beam Processing to Semiconductor Device Fabrication"
Prof. James F. Gibbons
Stanford University
Stanford, CA

2:15 "Voltage Contrast as an IC Diagnostic Tool" Dr. Anand Gopinath MIT Lincoln Lab Lexington, MA

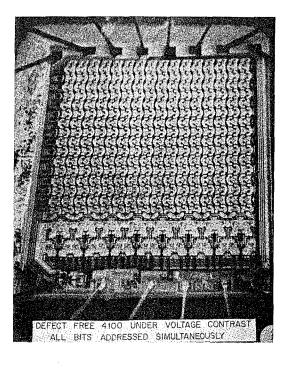
COFFEE BREAK 3:00

"Integrated Circuits as Viewed Through the Acoustic Microscope"
Prof. Calvin F. Quate
Stanford Chiversity

"Wafer Production Advantages of X-Ray Lithography Using a Synchrotron Radiation Source"
Dr. Warren D. Grobman
IBM T. J. Watson Research Center
Yorktown Heights, NY

HOSTED COCKTAIL PARTY (Circus Maximus North)

8:00 - 5:00 Vendors Exhibits (Circus Maximus South)



### **GENERAL INFORMATION**

- The registration fee for the symposium covers admission to symposium sessions, extended abstracts of symposium presentations, luncheon, a vendor's exhibit, and portion of a hosted cocktail hour following the symposium. Physical limitations require that attendance be limited to the first 350 registrants.
- 2. Costs for the symposium have been kept to a minimum to encourage attendance. A surcharge will be required from those who do not preregister by Monday, March 3, 1980 because of added costs for arrangements after that date. To reserve your place at the symposium and luncheon, we urge you to register early by mail, using the form provided. No refund of registration fees will be made after Monday, March 3, 1980.
- During the symposium, the sixth annual Ross N. Tucker Memorial Award will be presented to Richard Gold, Department of Electrical Engineering, Stanford University, for his work on developing materials for solid state solar energy
- 4. We are honored to have Stanford R. Ovshinsky as our luncheon speaker. His topic will be "Electronic and Energy Applications of New Amorphous Synthetic Materials."
- A feature of this symposium will be a vendor's exhibit. Information displays on new materials, processing equipment and analytical instruments will be presented by manufacturing representatives.
- A hosted cocktail party will follow the final symposium presentation, providing an opportunity for informal discussions with symposium speakers and guests.
- Registration material and extended abstracts of the symposium presentation will be available at the symposium. The opening session will begin promptly at 8:30 a.m.
- Further questions regarding the symposium should be directed to Robert D. Burnham, Xerox PARC, 3333 Coyote Hill Rd., Palo Alto, CA 94304. Telephone: (415) 494-4179.

### **ABOUT THE SPEAKERS**

DR. RICHARD C. EDEN was born in Anamosa, Iowa, on July 10, 1939. He received the BS degree from Iowa State University. Ames, the MS degree from the California Institute of Technology. Pasadena, and the PhD degree from Stanford University, all in Electrical Engineering. After receiving the MS degree, he worked at the Advanced Systems Development Laboratory of IBM, San Jose, California. His PhD dissertation work involved detailed electronic energy band studies on GaAs, GaP, and Si using photoemission work he extended after joining the Science Center/Rockwell International in 1968, to surface state observations on silicon by vacuum photoemission and internal photoemission in MOS structures. Following this, he carried out development work on high-speed, high-efficiency heterojunction III-V alloy 1.06 µm avalanche photodiodes and on ultrahigh sensitivity, high-speed hybrid-integrated preamplifiers for these detectors. He was also involved in the design and analysis of a number of special device structures including the recently successfully demonstrated GaAs CCD. His most recent efforts have been focused toward the development of a very high-speed ultralow power planar GaAs digital integrated circuit technology with gate densities and power dissipation levels compatible with LSI or VLSI. Currently, he is Principal Scientist for Solid State Electronics at the Rockwell International Science Center, Thousand Oaks, California. Dr. Eden is a member of the American Physical Society, Eta Kappa Nu, Tau Beta Pi, Phi Kappa Phi, Phi Eta Sigma, Pi Mu Epsilon, and Sigma Xi.

DR. JAMES F. GIBBONS was born in Leavenworth, Kansas, and educated at Northwestern University (BS, 1953) and Stanford (PhD, 1956). He held National Science Foundation and National Academy of Sciences Fellowships for his entire graduate study career (1953-1956), and was awarded a Fulbright Fellowship for post-doctoral research at Cambridge University, Cambridge, England, in 1956-1957. He joined the Stanford faculty in 1957, and was appointed Professor of Electrical Engineering in 1964. His principal scientific interests are in the areas of ion implantation, laser annealing and solar energy. He is a Fellow of the IEEE and a member of the National Academy of Engineering. He was awarded the Western Electric Fund Award for Excellence in Teaching in 1971.

DR. ANAND GOPINATH received the PhD degree from the University of Sheffield, England, in 1965 and was awarded the degree of Doctor of Engineering, also from Sheffield, in 1978. He taught at the University College of North Wales, Bangor, where he was Reader in Electronics, until 1978; since July 1978 he has been with M.I.T. Lincloln Laboratory. His interests are in the areas of: semiconductor devices and device physics, electron-beam probes and their applications in the device and processing areas, and microwave theory and techniques.

DR. WARREN D. GROBMAN received the BA degree in Physics from the University of Pennsylvania, Philadelphia, Pennsylvania, in 1964: and the MA and PhD degrees in Physics from Princeton University, Princeton, New Jersey, in 1966 and 1967, respectively. He was a member of the Technical Staff at Bellcomm Inc. from 1967 to 1969. In 1969, he joined the IBM Thomas J. Watson Research Center, Yorktown Heights, New York, as a Research Staff member. At IBM he has worked in the field of experimental photoemission spectroscopy and has done theoretical work on the electronic structure of solidis and in the area of many-body systems. Since 1976, he has worked in the area of high-resolution lithography. Currently, he is a Manager of a group responsible for applications of electron-beam lithography he is a Manager of the Stanford Storage Ring Laboratory. Dr. Grobman is a member of Sigma Xi, the American Physical Society, and the Electrochemical Society.

MR. STANFORD R. OVSHINSKY has worked in the field of amorphous films since 1957. In 1960, with his wife Iris, he founded Energy Conversion Devices, Inc., Troy, Michigan, to continue research and development in amorphous materials for use in various phases of information storage and control combined with the concepts of energy conversion. He is presently President of the company where, in addition to his recent developments utilizing amorphous materials for imaging, he has developed new amorphous materials for energy conversion use. He has over 60 U.S. patents, is the author of numerous scientific papers ranging from neurophysiology to amorphous semiconductors, and in 1968 was the recipient of the Diesel Gold Medal for Invention presented by the German Inventors Association. He is Adjunct Professor of Enigineering Sciences, College of Engineering, Wayne State University.

DR. RICHARD D. PASHLEY received the BA degree in Physics from the University of Colorado, Boulder, in 1969, and the MS and PhD degrees in Electrical Engineering from the California Institute of Technology, Pasadena, in 1970 and 1974, respectively. Presently, he is Manager of Static RAM Engineering at Intel Corporation, Santa Clara, California. His department is responsible for the development of the HMOS technologies and the 2125/214/ product lines. As an individual contributor he developed the technique of on-chip substrate back-biasing and holds several key MOS patents.

### CONFERENCE COMMITTEE

V. Marrello (IBM Corp.) G. B. Stringfellow (Hewlett-Packard Corp.)				(Intel Corp.) (Hewlett-Packard Corp.) (Lockheed Corp.) (Hewlett-Packard Corp.) (General Instruments Corp.)
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### CONFERENCE CHAIRMAN

Robert D. Burnham Xerox PARC 3333 Coyote Hill Road Palo Alto, California 94304 (415) 494-4179 DR. D. H. PHILLIPS provides technical leadership and direction to the Lockheed Microelectronics Center and company-sponsored programs to develop GaAs and Silicon Microelectronics technologies. He was General Chairman of the Gallium Arsenide Integrated Circuit Symposium in 1979 and Conference Chairman for the SOS Technology Workshop in 1978. He obtained the PhD degree in Electrical Engineering and Computer Science; and the MA degree in Nuclear Engineering Technical fields of interest include integrated circuit design, semiconductor device fabrications, and the analysis of transient and permanent radiation effects in semiconductor and dielectric materials.

DR. CALVIN F. QUATE was born in Baker, Nevada. He received the BS degree in Electrical Engineering from the University of Utah in 1944, and the PhD degree from Stanford University in 1950. In 1949, he joined the technical research staff at Bell Laboratories in Murray Hill, New Jersey, where he was later appointed Associate Director of Electronics Research. He joined Sandia Corporation in Albuquerque, New Mexico, in 1959; and in 1960, became Vice President and Director of Research. Stanford University appointed him Professor of Applied Physics and Electrical Engineering in 1961; in 1969 he assumed the Chairmanship of the Applied Physics Department at Stanford and held this position until 1972. In 1970 he was elected to membership in the National Academy of Engineering. From 1972-1974 he served as an Associate Dean in the School of Humanities and Sciences at Stanford. In 1975 he was elected to membership in the National Academy of Sciences. In 1978 he accepted the Chairmanship of the Applied Physics Department for a second term. Dr. Quate's major research interest is in the field of acoustic imaging. He is the author and co-author of 100 scientific publications. He is a member of Tau Beta Pi, Sigma Xi, the American Physical Society, the Acoustical Society and a fellow of the IEEE.

## REGISTRATION FORM

# 1980 EIGHTH AIME ELECTRONIC MATERIALS SYMPOSIUM

			Zip Code		Payment Received After March 3, 1980	\$33.00	\$38.00	\$20.00
Title			State		Payment Received Before March 3, 1980	\$23.00	\$28.00	\$10.00
Name	Organization	Mailing Address	City	Registration Fee:		( ) AIME Member	( ) Non-Member	( ) Full-Time

e above information to: Robert D. send Purchase Orders. Please make the information requested above and Make checks payable to: "No. Cal. Met. Section, AIME," and send with the Burnham, Xerox PARC. 3333 Coyote Hill Rd., Palo Alto, CA 94304. Do not sure your name and affiliation are identified. Others may register by supplying t sending it with the registration fee.

ATTEND TO WISH MAY WHO COLLEAGUES YOUR PLEASE SHARE THIS INFORMATION WITH SYMPOSIUM.